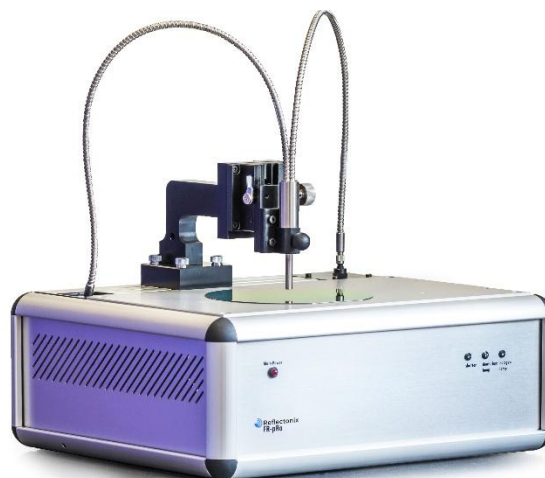


FR-pRo: the modular & expandable platform for non-destructive characterization of coatings in the **1nm-3mm** thickness range.

FR-pRo tools are tailored to meet any user need for a wide range of diverse applications, such as: Film thickness, Refractive Index, Color, Transmittance, Reflectance, Film Characterization under temperature or ambient controlled environment or in liquid environment and many more ...

Applications

- **Univ. & Research labs**
- **Semiconductors**
- **Polymer & Resist characterization**
- **Concentration measurements of chemicals**
- **Dielectric characterizations**
- **Biomedical**
- **Hardcoats,**
- **Anodization**
- **Optical Coating**
- **non-metal Films**
- **And many more...**



FR-pRo tool is assembled by user selected modules. The Core Unit accommodates the light source, the spectrometer (for any spectral regime in the 190nm-2500nm range) and the control & communication electronics. The tool comes with a set of reference samples (Si reference, SiO₂/Si, Si₃N₄/SiO₂/Si). Then, there is a wide range of Accessories, such as:

- **Film Thickness kit** for reflectance measurements,
- **FR-Mic** for measurements at very small areas,
- **Manual & Motorized stages,**
- **Film/Cuvette Holder** for Absorbance / Transmittance and chemical concentration measurements,
- **Thermal or Liquid kits** for measurements under controlled Temperature or in Liquid environment,
- **Integration Spheres** for diffuse & total reflectance

By the combination of different modules, the final set-up meets any end-user needs

Specifications

Model	UV/VIS	UV/NIR-HR	D UV/NIR	VIS/NIR	D VIS/NIR	NIR	NIR-N1	NIR-N2	NIR-N3	NIR-N4
WL Range -nm	200 – 850	190-1100	200 – 1700	380 –1020	380 – 1700	900 – 1700	850-1050	900 - 1050	1280-1350	1520-1580
Pixels	3648	2048	3648 & 512	3648	3648 & 512	512	3648	3648	512	512
Min Thick -SiO ₂	1nm	1nm	1nm	12nm	12nm	50nm	1µm	4µm	12µm	20µm
Max Thick SiO ₂	80µm	100µm	250µm	120µm	250µm	250µm	500µm	1.0mm	2mm	3mm
Max Thick -Si							300µm***	450µm***	1mm***	1.3mm***
n&k -Min Thick	50nm	50nm	50nm	100nm	100nm	500nm		-	-	-
Thick. Accuracy	1nm / 0.2%	1nm / 0.2%	1nm / 0.2%	2nm / 0.2%	2nm / 0.2%	3nm / 0.2%	50nm / 0.2%	50nm / 0.2%	50nm / 0.2%	50nm / 0.2%
Thick.	0.05nm			0.05nm	0.05nm	0.1nm	0.1nm	5nm	5nm	5nm
Thick. stability	0.05nm			0.05nm	0.05nm	0.15nm	0.15nm	5nm	5nm	5nm
API support	YES			YES	YES	YES	YES	YES	-	-
Light Source	Internal Deuterium (2000h) & Halogen			Halogen (internal), 3000h (MTBF)					SLED (150Kh)	
Integration	5msec (min)			5msec (min)					20msec (min)	
Size/Weight	FR-pRo: 39x32x17cm (LxWxH) 10Kg, FR-pRo D: 45x32x19cm (LxWxH) 13Kg									
Power	110V/230V, 50-60Hz									
Spot size	Diameter of ~350-400µm (smaller spot size options are available upon request)									
Material	> 850 different materials									
SW	FR-Monitor v4.0 (free of charge updates) Full S/W details are listed at the related catalog's page									

Accessories

Film/Cuvette kit	Transmission measurements of films or liquids in standard cuvettes
Transmittance stage	Stage upgrade to support transmittance measurements
Lens Module	-Measurements on coatings where a small spot-size is required
Contact probe	Thickness & optical measurements of coatings in the field. Ideal for curved surfaces
Microscope	Microscope-based reflectance / transmittance and thickness measurements with high lateral resolution
Scanner (motorized)	Polar (R-O) or Cartesian (X-Y) automated stage with wafer chuck. Reflectance& transmittance
Integration sphere	For the characterization of specular and diffuse reflectance of coatings and surfaces
Manual X-Y stage	Manual X-Y stage for measurements over an area of 100mm x 100mm or 200mm x 200mm
Thermal Module	Computer controlled Hot plate embedded in the FR-tool (Room temperature - 200°C, 0.1°C accuracy)

* Specifications are subject to change without any notice; ** Thickness range depends on the spectral range and refers to a single layer with refractive index ~1.5 on Si substrate ** Measurements compared with a calibrated spectroscopic ellipsometer and XRD, Average of standard deviation of mean value over 15 days. Sample: 1µm SiO₂ on Si, Standard deviation of 100 thickness measurements. Sample: 1µm SiO₂ on Si, 2*Standard-Deviation of daily average over 15 days. Sample: 1µmicron SiO₂ on Si.